



PATENT  
3430-0149P

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: Jeong-Jin KIM et al. Conf. No.: 5548  
Appl. No.: 09/727,516 Group: 1765  
Filed: December 4, 2000 Examiner: A. K. ALANKO  
For: METHOD OF ETCHING AND CLEANING OBJECTS

**AMENDMENT AFTER FINAL**

**MS AF**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Examiner's Office Action dated October 5, 2005 and in view of the Request for Continued Examination (RCE) being filed concurrently herewith, the period for response having been extended one (1) month to February 6, 2006 (Monday), Applicants respectfully submit the following Remarks in connection with the above-identified application.

**This reply includes:**

**Amendments to the Claims;**

**Remarks.**